

### Advantages of Miniaturization

**Portable Gas Chromatograph**

19" Width  
13" Height  
Depth = 10"

**Chip-Scale Gas Chromatograph**

1-2 cm Length  
5 mm Height

**Reduction Factors**

Size	40,500 cm <sup>3</sup>	20,000X	Size	2 cm <sup>3</sup>
Sensitivity	1 ppb	1,000X	Sensitivity	1 ppt
Analysis Time	15 min.	225X	Analysis Time	4 sec
Energy Per Analysis	10,000 J	10,000X	Energy Per Analysis	1 J

### Basic Approach: Separation Analyzer

**Tiny Dimensions**

- fast time constants
- 10,000X gain factor via multi-staging
- enhanced sensitivity
- lower power

**Tiny Dimensions**

- faster separation
- lower power

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### Scaling Leads to Faster Separation

- **Example:** gas chromatograph separation column
  - ↳ unique analyte interactions with the column walls
  - ↳ different analyte velocities
  - ↳ **result:** separation after a finite distance

Wide Channel

Carrier Gas (Mobile Phase)

Peak Broadens

Thin Channel

Carrier Gas (Mobile Phase)

Peak Stays Thin

Miniaturize ⇒ Less Separation Needed to Resolve

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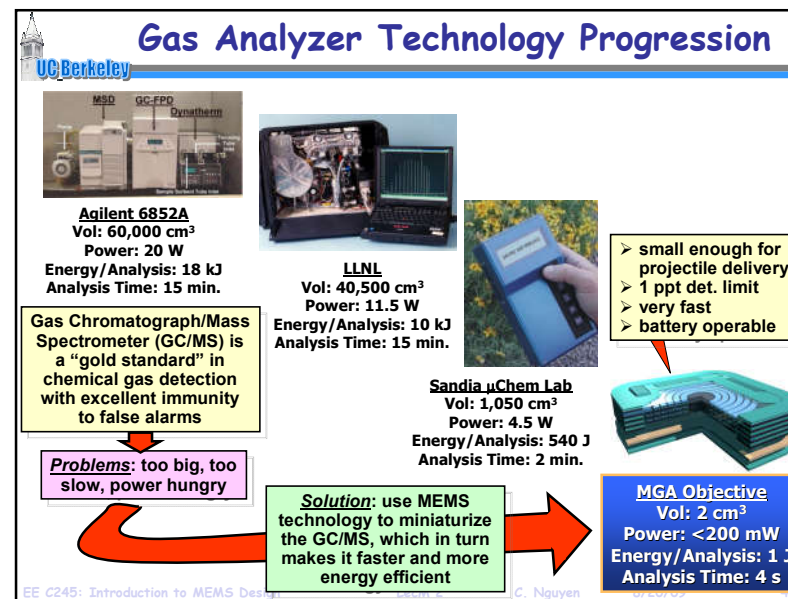
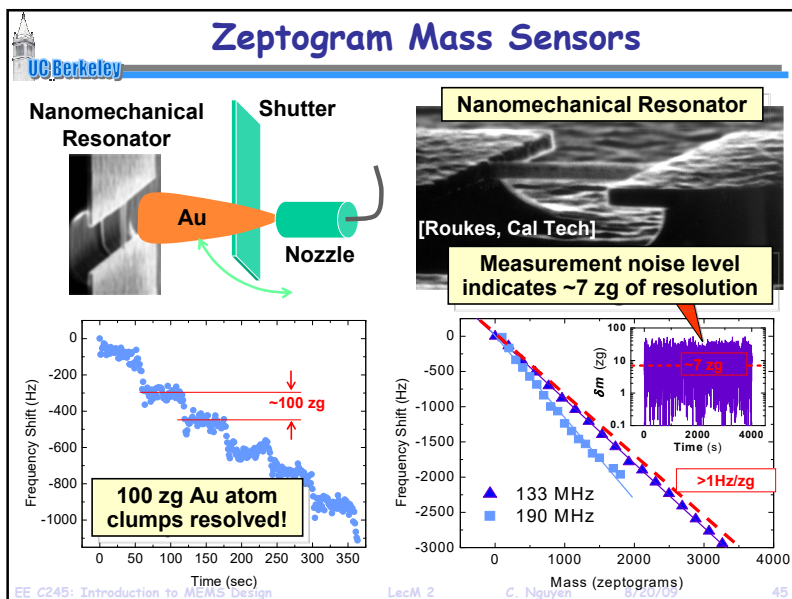
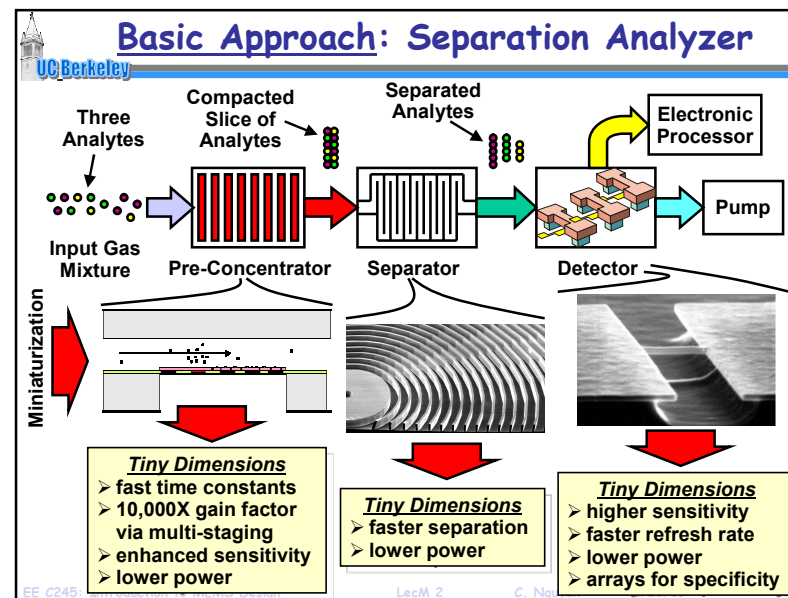
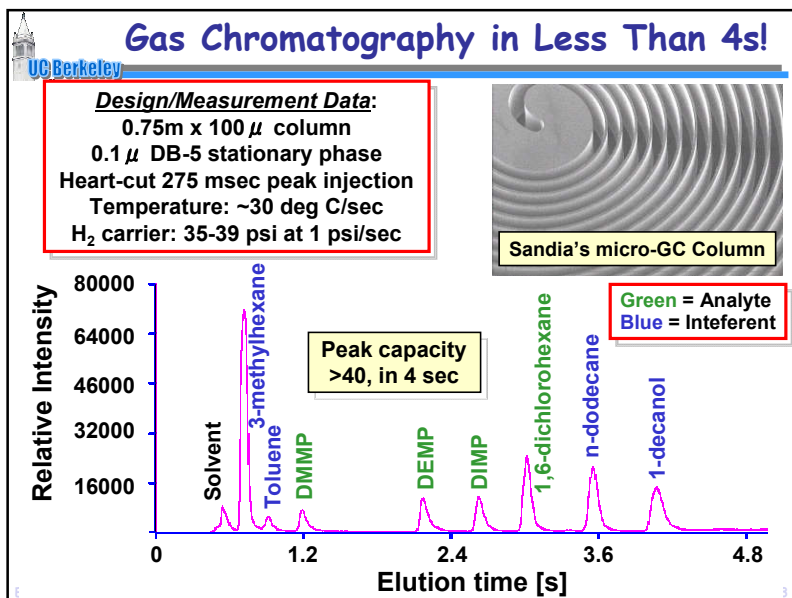
Thin Channel

Carrier Gas (Mobile Phase)

Column Width ↓ ⇒ Surface-to-Volume Ratio ↑ ⇒ Peak Spreading ↓ ⇒ Separation Distance ↓

- **Result of Scaling:** shorter column length; faster analysis time

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**Example: Micromechanical Accelerometer**

**The MEMS Advantage:**

- >30X size reduction
- allows integration

Tiny mass means small output  $\Rightarrow$  need integrated transistor circuits to compensate

**Basic Operation Principle**

$x \propto F_i = ma$

Displacement  
 Spring  
 Inertial Force  
 Proof Mass  
 Acceleration

Analog Devices ADXL 78

400  $\mu\text{m}$

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**Messages Going Forward ...**

- MEMS are micro-scale or smaller devices/systems that operate mainly via a mechanical or electromechanical means
- MEMS  $\Rightarrow$  NEMS offer the same scaling advantages that IC technology offers (e.g., speed, low power, complexity, cost), but they do so for domains beyond electronics:
  - resonant frequency  $\uparrow$  (faster speed)
  - actuation force  $\downarrow$  (lower power)
  - # mechanical elements  $\uparrow$  (higher complexity)
  - integration level  $\uparrow$  (lower cost)

Size  $\downarrow$   $\Rightarrow$

- Micro ... nano ... *it's all good*
- Just as important: MEMS or NEMS have brought together people from diverse disciplines  $\Rightarrow$  this is the key to growth!
- What's next?  $\Rightarrow$  Nano-nuclear fusion? Chip-scale atomic sensors?

**... limitless possibilities ...**

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